

Docket No. 210136US99



AP

15-2812
X

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Ravindranath DROOPAD et al.

SERIAL NO: 09/901,109

GAU: 2812

FILED: July 10, 2001

EXAMINER: BOOTH, R.A.

FOR: STRUCTURE AND METHOD FOR FABRICATING SEMICONDUCTOR STRUCTURES AND DEVICES UTILIZING THE FORMATION OF A COMPLIANT SUBSTRATE COMPRISING AN OXYGEN-DOPED COMPOUND SEMICONDUCTOR LAYER

EXPRESS ABANDONMENT UNDER 37 CFR 1.138

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

☒ **Express Abandonment**

Applicant's Representative requests that the above-identified application be expressly abandoned as of the filing date of this paper.

☐ **Express Abandonment in Favor of a Continuing Application**

Applicant's Representative requests that the above-identified application be expressly abandoned as of the filing date accorded the continuing application filed herewith.

☐ **Petition for Express Abandonment to Avoid Publication under 37 C.F.R. 1.138(c)**

Applicant's Representative hereby petitions to expressly abandon the above-identified application under 37 CFR 1.138(c) to avoid publication.

The required petition fee under 37 CFR 1.17(h) of \$130.00 is enclosed herewith by credit card payment form and any further charges may be made against the Attorney of Record's Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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130.00 OP

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
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